

**2015**

**M.Sc.**

**4th Semester Examination**

**ELECTRONICS**

**PAPER—ELC-404**

*Full Marks : 50*

*Time : 2 hours*

*The figures in the right-hand margin indicate full marks.*

*Candidates are required to give their answers in their own words as far as practicable.*

*Illustrate the answers wherever necessary.*

**(VLSI Technology)**

Answer Q. No. 1 and any three from the rest.

1. (a) What is gettering?
- (b) How is a silicon dioxide layer grown for masking in VLSI technology?
- (c) Mention the advantages and disadvantages of electron beam lithography.

*(Turn Over)*

- (d) What is CMOS latchup ?  
 (e) What do you understand by hard yield and soft yield ?

2×5

2. (a) Describe an ion implantation system with a schematic diagram.  
 (b) What are the problems entangles in ion implantation ?  
 How can that be solved ?  
 (c) Mention SIMOX process and its uses.

3+(2+2)+(2+1)

3. (a) Describe electron cyclotron resonance (ECR) plasma etching with a schematic diagram of an ECR reactor.  
 (b) The electron densities in reactive ion etching (RIE) and high-density plasma (HDP) systems range from  $10^9$  to  $10^{10}$   $\text{cm}^{-3}$  and  $10^{11}$  to  $10^{12}$   $\text{cm}^{-3}$  respectively. Assuming the RIE chamber pressure is 200 mT and HDP chamber pressure is 5 mT. Calculate the ionization efficiency in RIE reactors and HDP reactors at room temperature.  
 (c) Explain the role of  $\text{O}_2$  in plasma etching of Si in  $\text{CF}_4 + \text{O}_2$  plasma.

4+(2+2)+2

4. (a) What are the different types of voltage break-down mechanism present in MOSFETs?
- (b) How does a LDD structure reduce short channel effects?
- (c) Explain a DMOS structure with a schematic diagram. Mention its merits and demerits.

2+3+(3+2)

5. (a) Draw a schematic diagram of a three phase CCD.
- (b) Explain the operation of the CCD with potential energy and charge distribution of the device on the applications of clock pulses. Draw the clock wave forms and output signal.
- (c) A three-phase n-type surface-channel CCD has the following specifications :

Electron density :  $N_{\max} = 2 \times 10^{12} \text{ cm}^{-2}$

Relative dielectric constant of the insulator :  $\epsilon_{\text{ir}} = 3.9$

Insulator thickness :  $d = 0.15 \mu\text{m}$

Insulator cross section :  $A = 0.5 \times 10^{-4} \text{ cm}^2$

Power dissipation allowable per bit :  $P = 0.67 \text{ mW}$

- (i) Determine the maximum stored charges per well.

- (ii) Find the required applied gate voltage.  
 (iii) Choose the clock frequency.

$$2+(3\frac{1}{2}+1\frac{1}{2})+(1+1+1)$$

6. (a) What are the Moore's law and Rent's rule?  
 (b) Estimate the number of gates that can be included on a logic-gate array chip which is to be assembled in pin grid array package. Consider the Rent's exponent 0.5 and the average number of terminals required by a single logic block 4.5.  
 (c) Mention the different electrical performance criteria considered at the IC package. How is the most important practical electrical design problem in IC packages reduced?

$$(2+2)+2+(2+2)$$

### Internal Assessment — 10

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